

08/733,555, filed October 1, 1996 (now issued as Patent No. 6,063,233), which is a continuation-in-part of application Serial No. 08/648,254, filed May 13, 1996 (now issued as Patent No. 6,165,311), which is a continuation-in-part of application Serial No. 08/580,026, filed December 20, 1995 (currently pending), which is a continuation of application Serial No. 08/041,796, filed April 1, 1993 (now abandoned), which is a continuation of application Serial No. 07/722,340, filed June 27, 1991 (now abandoned). This application is furthermore a continuation-in-part of application Serial No. 08/503,467, filed July 18, 1995 (now issued as Patent No. 5,770,099), which is a divisional of application Serial No. 08/138,060, filed October 15, 1993 (now issued as Patent No. 5,477,975). This application is furthermore a continuation-in-part of application Serial No. 08/597,577, filed February 2, 1996 (now issued as Patent No. 6,077,384), which is a continuation-in-part of application Serial No. 08/521,668, filed August 31, 1995 (now abandoned), which is a continuation-in-part of application Serial No. 08/289,336, filed August 11, 1994 (now abandoned), which is a continuation of application Serial No. 07/984,045, filed December 1, 1992 (now abandoned). In addition, U.S. application Serial No. 08/648,265 filed May 13, 1996 (now issued as Patent No. 6,165,311) discloses related subject matter.---

In the claims:

Please amend claim 1 as follows:

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1. (Once Amended) For use in a plasma reactor including a plasma reactor chamber, a workpiece support for holding a workpiece inside said chamber during processing and an inductive antenna,